

# **Europe TC Chapter Compound Semiconductor Materials Global Technical Committee**

## **Liaison Report**

**August 6, 2021**

**v1**

# Meeting Information

- Last meeting
  - July 29, 2021
    - Online via Official Virtual TC Chapter Meeting
    - 4:30 – 6:30 PM CET
- Next meeting
  - November 17, 2021
    - Messe Muchen, Munich, Germany
    - 11:00 AM – 1:00 PM CET

<http://www.semi.org/en/standards-events>

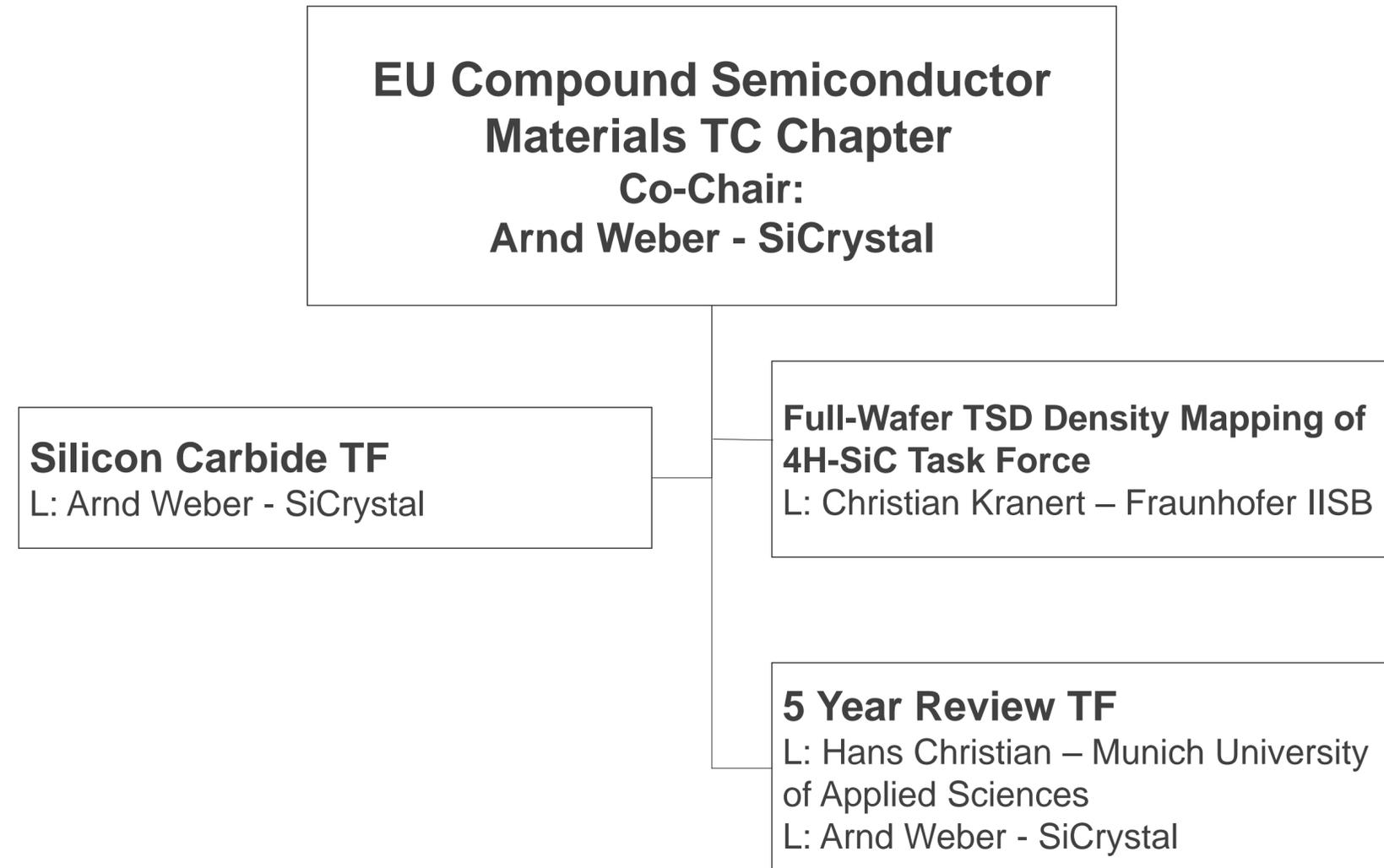
# Leadership

- Co-Chair: Arnd Weber (SiCrystal)



- 2<sup>nd</sup> Co-Chair position currently open

# Organization Chart



# Ballot Result

Doc #	Title	Committee Action
6779	Reapproval of SEMI M64-0915 Test Method For The E12 Deep Donor Concentration In Semi-Insulating (Si) Gallium Arsenide Single Crystals By Infrared Absorption Spectroscopy	Passed as balloted
6780	Line Item Revision of SEMI M87-0116 Test Method For Contactless Resistivity Measurement Of Semi-Insulating Semiconductors	Passed as balloted

# Authorized Ballots

Doc #	Cycle	SC/TF/WG	Details
6717	Cycle 6-21	Full-Wafer TSD Density Mapping of 4H-SiC Task Force	New Standard: Test Method For Determination Of Threading Screw Dislocation Density In 4H-SiC By X-Ray Topography

# Task Force Highlights [1/2]



- SiC TF
  - Leader
    - Arnd Weber (SiCrystal)
  - Doc. 6615, Revision of M55-0817 Specification for Polished Monocrystalline Silicon Carbide Wafers
    - To include 200 mm wafer for Silicon Carbide
  - Ballot passed and forwarded to ISC A&R
  - Publication is pending.
  
- Full-Wafer TSD Density Mapping of 4H-SiC TF
  - Leader
    - Christian Kranert (Fraunhofer)
  - Issued doc. 6716, New Standard: Test Method for Quantifying Threading Screw Dislocations (TSDs) in 4H-SiC Crystals for cycle 6-2021

# Task Force Highlights [2/2]



- 5 Year Review TF

- Leaders

- Hans Christian – Munich University of Applied Sciences
    - Arnd Weber (SiCrystal)

- Reviewing Standards due for 5 year review

- SEMI M46 - Test Method for Measuring Carrier Concentrations in Epitaxial Layer Structures by ECV Profiling
      - Needs more time
    - SEMI M63 - Test Method for Measuring the Al Fraction in AlGaAs on GaAs Substrates by High Resolution X-Ray Diffraction
      - Requesting other TC Chapter from other regions to take a look
    - SEMI M75 - Specification for Polished Monocrystalline Gallium Antimonide Wafers
      - Needs experts for review

# Thank you!

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